

# Active Thermal Probe

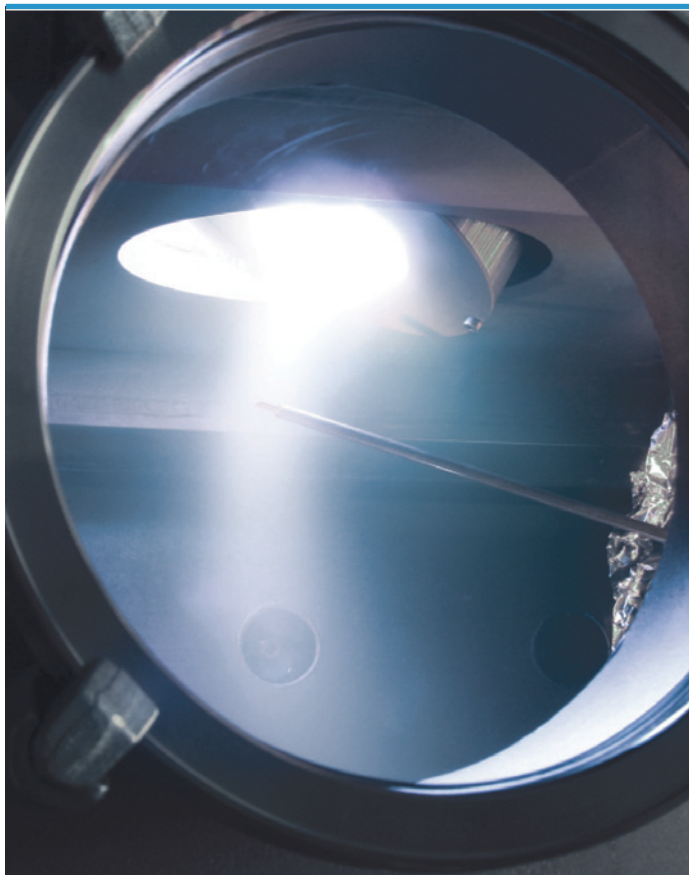


## technical specification

The characterization, control and monitoring of plasma processes is crucial for the production of high quality coatings and material properties. A parameter of paramount importance is the actual and total energy influx to the substrate – the active thermal probe is the single tool to measure this decisive quantity.

Incoming particles influence surface processes and reactions at the substrate. This energy along with other components like thermal radiation or chemical energy comprises the total energy influx. The active thermal probe measures continuously and directionally this influx and correlates well with layer and surface properties.

Due to the probe's very high sensitivity it is especially suitable for cost-effective quality control in industrial processes or for research purposes. A special version with a bigger selection of adjustable parameters is available to address R&D of plasma processes.



## general

suitable for vacuum

temperature resistant up to 450°C

energy influx up to  $(2 \pm 0,001)$  W/cm<sup>2</sup> measurable

variable length and geometry

includes software package for system control and evaluation

installation service and consulting on process optimization is possible